

Amendments to the Claims:

Please amend claims 1 and 4 and add new claims 9-13 as follows. The following listing of claims will replace all prior versions, and listings, of claims in the application.

Listing of Claims:

Claim 1 (Currently Amended). A wafer holding device for use in an apparatus for treating a principal surface of a semiconductor wafer under a predetermined heating condition while the back surface of said principal surface of the wafer is held
5 by the device at a predetermined position within a chamber of said apparatus, said device comprising:

a susceptor formed in the surface thereof with a wafer loading area for supporting the back surface of the wafer,

a plurality of support pins each arranged at one of four
10 equiangularly spaced positions along a circumference of ~~at least one~~ each of a plurality of concentric circle circles in said wafer loading area so as to protrude from the surface of said susceptor, and

a resilient mechanism made from quartz for supporting said
15 support pins.

Claim 2 (Previously Presented). The wafer holding device according to claim 1, wherein said support pins are disposed in position which support the wafer along the crystal orientation with respect to the crystal plane of the wafer.

Claim 3 (Previously Presented). The wafer holding device according to claim 1, wherein said resilient mechanism includes a plurality of flexible members made from quartz each supporting one of said support pins.

Claim 4 (Currently Amended). A wafer holding device adapted for use in an apparatus for treating a principal surface of a semiconductor wafer under a predetermined heating condition while the back surface of said principal surface of the wafer is held by the device at a predetermined position within a chamber of said apparatus, said device comprising:

a susceptor formed in the surface thereof with a wafer loading area of supporting the back surface of the wafer, and

a plurality of support pins each arranged at one of four equiangularly spaced positions along a circumference of ~~at least one~~ each of a plurality of concentric circle circles in said wafer loading area so as to protrude from the surface of said

susceptor, each of said support pins including a resilient
mechanism, wherein said resilient mechanism includes a plurality
15 of flexible members each supporting one of said support pins,
wherein each said flexible member comprises a leaf spring
made from quartz.

Claims 5-8 (Cancelled).

Claim 9 (New). The wafer holding device according to claim
4, wherein said support pins are disposed in positions which
support the wafer along the crystal orientation with respect to
the crystal plane of the wafer.

Claim 10 (New). The wafer holding device according to
claim 1, wherein said support pins are arranged on three
concentric circles at regular angular intervals of 90-degrees so
that every four of the support pins are arranged on each of three
5 concentric circles thereby arranging the twelve support pins in
total.

Claim 11 (New). The wafer holding device according to
claim 2, wherein said support pins are arranged on three

concentric circles at regular angular intervals of 90-degrees so
that every four of the support pins are arranged on each of three
5 concentric circles and every three of said support pins are
arranged on each of the four radii each corresponding to said
crystal orientation, thereby arranging the twelve support pins in
total.

Claim 12 (New). The wafer holding device according to
claim 4, wherein said support pins are arranged on three
concentric circles at regular angular intervals of 90-degrees so
that every four of the support pins are arranged on each of three
5 concentric circles thereby arranging the twelve support pins in
total.

Claim 13 (New). The wafer holding device according to
claim 9, wherein said support pins are arranged on three
concentric circles at regular angular intervals of 90-degrees so
that every four of the support pins are arranged on each of three
5 concentric circles and every three of said support pins are
arranged on each of the four radii each corresponding to said
crystal orientation, thereby arranging the twelve support pins in
total.